

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: SORAOKA et al

Serial No.: 10/689,035

Filed: October 21, 2003

For: Vacuum Processing Apparatus And Semiconductor
Manufacturing Line Using The Same

Group: 3652

Examiner: T. Brahan

INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR 1.97 & 1.98

Mail Stop: DD
Commissioner For Patents
P.O. Box 1450
Alexandria, VA 22313-1450

March 26, 2004

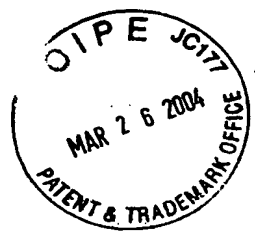
Sir:

In the matter of the above-identified application, applicants are submitting herewith copies of the documents listed in the attached form equivalent to Form PTO-1449 for the Examiner's consideration. These documents are being considered by applicants and the undersigned in connection with a continuing application.

This information disclosure statement is being submitted before the mailing date of a first office action on the merits.

To the extent the documents listed on the attached form equivalent to Form PTO-1449 are not in the English language, the requirement of 37 CFR 1.98(a)(3) for a concise explanation of the relevance is satisfied by English translations from the Japanese Patent Office.

It is respectfully requested that this information disclosure statement be

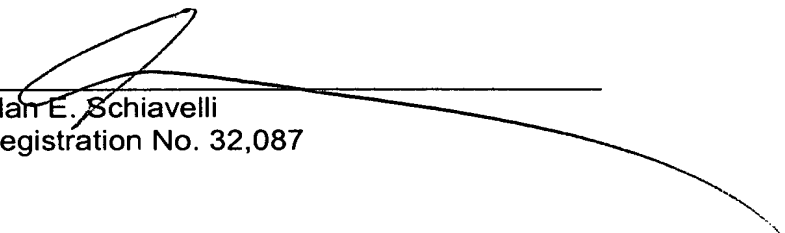


considered by the Examiner.

Please charge any shortage in the fees due in connection with the filing of this paper, including extension of time fees, to the deposit account of Antonelli, Terry, Stout & Kraus, LLP, Deposit Account No. 01-2135 (Case: 520.34692V16), and please credit any excess fees to such deposit account.

Respectfully submitted,

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